



INFORMATION DISCLOSURE STATEMENT BY APPLICANT

Complete if Known

Application Number	10/724,136
Filing Date	12/1/03
First Named Inventor	A. Buerke et al.
Art Unit	2811
Examiner Name	Unknown
Attorney Docket Number	INF-118

Sheet	1	of	2
-------	---	----	---

[illegible][illegible]

Examiner Signature	HUNG VU	Date Considered	08/28/04
-----------------------	---------	--------------------	----------

* EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

Burden Hour Statement: This form is estimated to take 2.0 hours to complete. Time will vary depending upon the needs of the individual case. Any comments on the amount of time you are required to complete this form should be sent to the Chief Information Officer, U.S. Patent and Trademark Office, Washington, DC 20231. **DO NOT SEND FEES OR COMPLETED FORMS TO THIS ADDRESS. SEND TO: Assistant Commissioner for Patents, Washington, DC 20231.**

Under the Paperwork Reduction Act of 1995, no persons are required to respond to a collection of information unless it contains a valid OMB control number.

Substitute for form 1449B/PTO		Complete if Known			
INFORMATION DISCLOSURE STATEMENT BY APPLICANT (use as many sheets as necessary)		Application Number	10/724,136		
		Filing Date	12/1/03		
		First Named Inventor	A. Buerke et al.		
		Group Art Unit	2811		
		Examiner Name	Unknown		
Sheet	2	of	2	Attorney Docket Number	INF-118

OTHER PRIOR ART -- NON PATENT LITERATURE DOCUMENTS			
Examiner Initials	Cite No. ¹	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published.	T ²
<u>Vu</u>		M. Takeyama et al. "Preparation of Wn Films and Their Diffusion Barrier Properties in CU/Si Contact System" Jpn. J. Appl. Phys. Vol. 36 (1997) pp. 2261-2266.	<input type="checkbox"/>
<u>Vu</u>		Y. Kim et al. "New Method to Improve the Adhesion Strength of Tungsten Thin Film on Silicon W2N Glue Layer" App. Phys. Lett. 61 (5) 1992 pp. 537-539	<input type="checkbox"/>
<u>Vu</u>		B. Lee et al. "In situ Barrier Formation Using Rapid Thermal Annealing of a Tungsten Nitride/Polycrystalline Silicon Structure" Applied Physics Letters, Vol. 76 (18) 2000 pp. 2538-2540	<input type="checkbox"/>
<u>Vu</u>		B. Suh, et al. "Crystallization of Amorphous Wn Films" J. Appl. Phys. Vol. 89 (2000), pp 4128-4133.	<input type="checkbox"/>
			<input type="checkbox"/>
			<input type="checkbox"/>
			<input type="checkbox"/>
			<input type="checkbox"/>
			<input type="checkbox"/>
			<input type="checkbox"/>

Examiner Signature	HUNG VU	Date Considered	02/28/04
--------------------	---------	-----------------	----------

* EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

¹ Applicant's unique citation designation number (optional). ² Applicant is to place a check mark here if English language Translation is attached.

Burden Hour Statement: This form is estimated to take 2.0 hours to complete. Time will vary depending upon the needs of the individual case. Any comments on the amount of time you are required to complete this form should be sent to the Chief Information Officer, U.S. Patent and Trademark Office, Washington, DC 20231. DO NOT SEND FEES OR COMPLETED FORMS TO THIS ADDRESS. SEND TO: Assistant Commissioner for Patents, Washington, DC 20231.